

## Supplementary Information

### An Electrochemical Thermal Transistor

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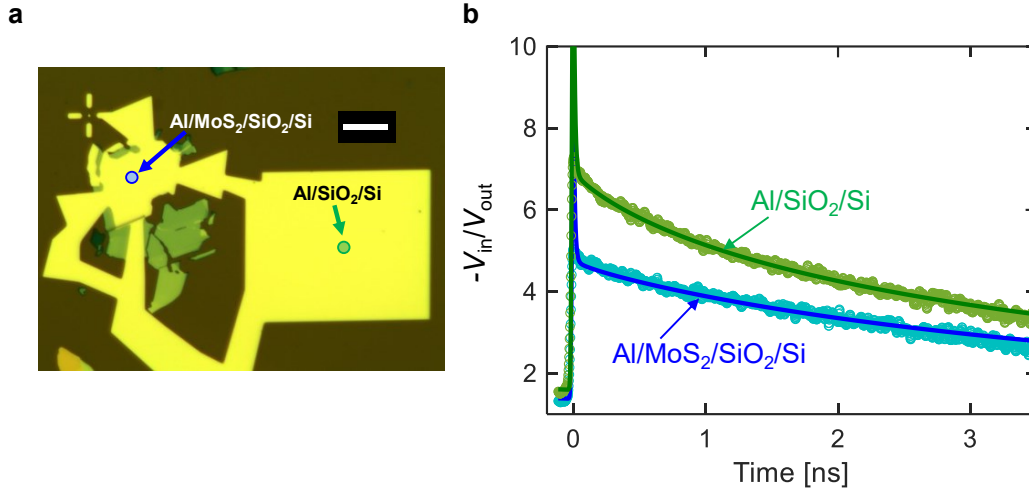
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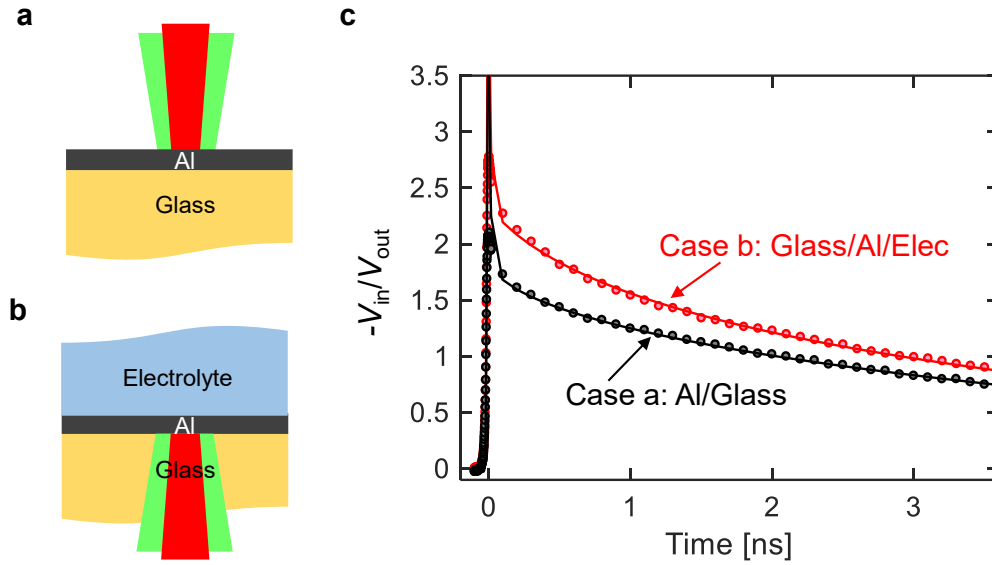
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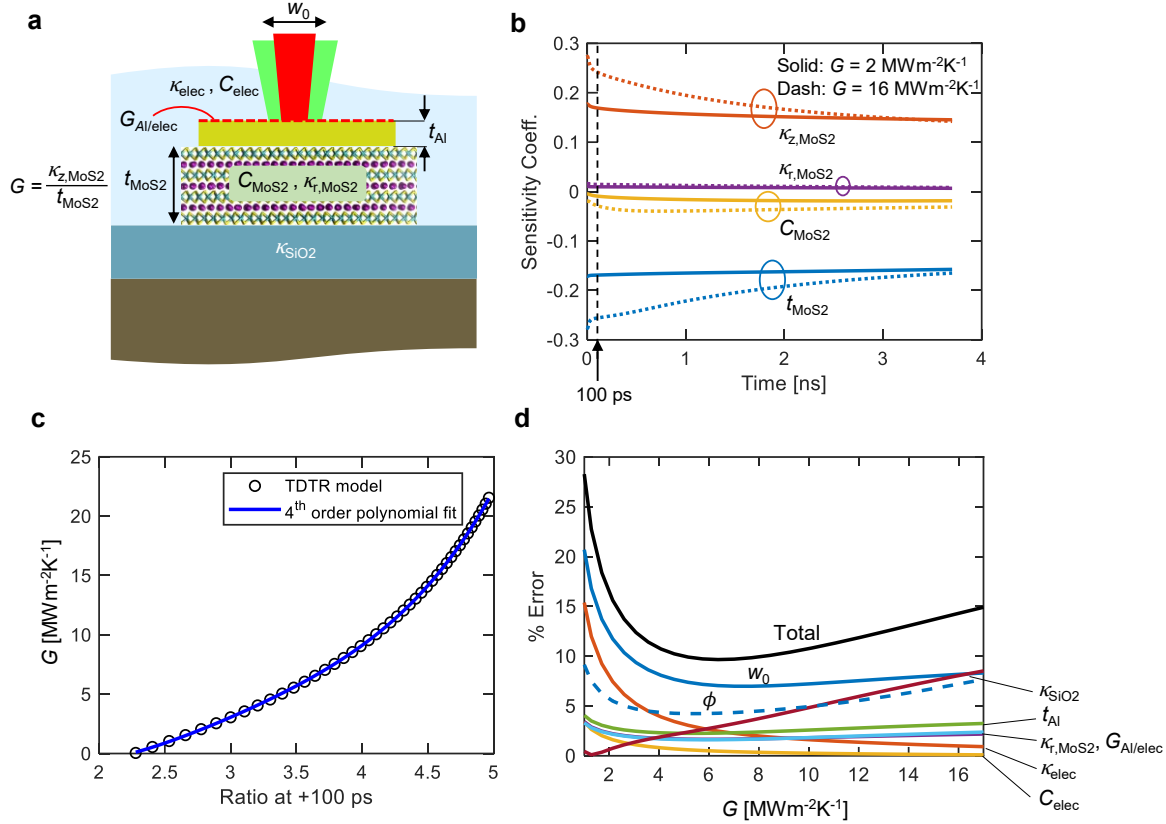
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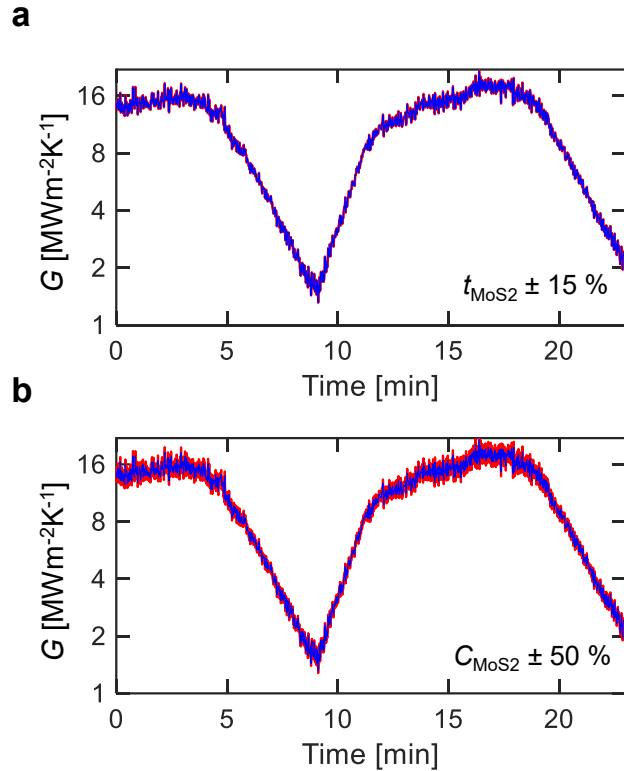
**Supplementary Figure 1 | Time-domain thermoreflectance (TDTR) measurements on the Al/SiO<sub>2</sub>/Si reference pad, and Al/MoS<sub>2</sub>/SiO<sub>2</sub>/Si pristine (unlithiated) MoS<sub>2</sub> device.** **a**, Optical micrograph of the device, indicating the locations where measurements are made. The scale bar is 10 μm. **b**, Measured TDTR time-decay curves and best fits to the thermal model. Measurements on the reference pad give the thermal conductivity of SiO<sub>2</sub>,  $\kappa_{\text{SiO}_2} = 1.4 \pm 0.1 \text{ Wm}^{-1}\text{K}^{-1}$ , and the thermal boundary conductance at the Al/SiO<sub>2</sub> interface,  $G_{\text{Al/SiO}_2} = 90 \pm 10 \text{ MWm}^{-2}\text{K}^{-1}$ , which are comparable to those reported in literature<sup>1</sup>, validating the accuracy of our setup and analysis methodology. Measurements on the MoS<sub>2</sub> region give the effective cross-plane thermal conductance  $G$ , such that  $1/G$  is the series sum of the Al/MoS<sub>2</sub> and MoS<sub>2</sub>/SiO<sub>2</sub> interfacial resistances and the MoS<sub>2</sub> volumetric resistance. We extract a value of  $G = 15 \pm 2 \text{ MWm}^{-2}\text{K}^{-1}$ . The error bars are based on uncertainties in the Al thickness  $t_{\text{Al}}$  ( $\pm 1 \text{ nm}$ ), laser spot size  $w_0$  ( $\pm 2 \%$ ), SiO<sub>2</sub> conductivity  $\kappa_{\text{SiO}_2}$  ( $\pm 0.1 \text{ Wm}^{-1}\text{K}^{-1}$ ), and the MoS<sub>2</sub> in-plane conductivity  $\kappa_{\text{r,MoS}_2}$  (which we vary in the range<sup>2,3</sup>  $45 - 85 \text{ Wm}^{-1}\text{K}^{-1}$ ). Relatively large uncertainties in  $\kappa_{\text{r,MoS}_2}$  lead to only  $\sim 2 \%$  errors in  $G$ . We also include errors resulting from uncertainties in setting the reference phase angle  $\Phi$  on the lock-in amplifier. This is estimated by dividing the root-mean-square noise in the out-of-phase voltage ( $V_{\text{out}}$ ) averaged between  $-100$  to  $+100 \text{ ps}$  by the jump in the in-phase voltage ( $V_{\text{in}}$ ) at zero delay time; we estimate  $\delta\Phi \approx 3 \text{ mrad}$ .



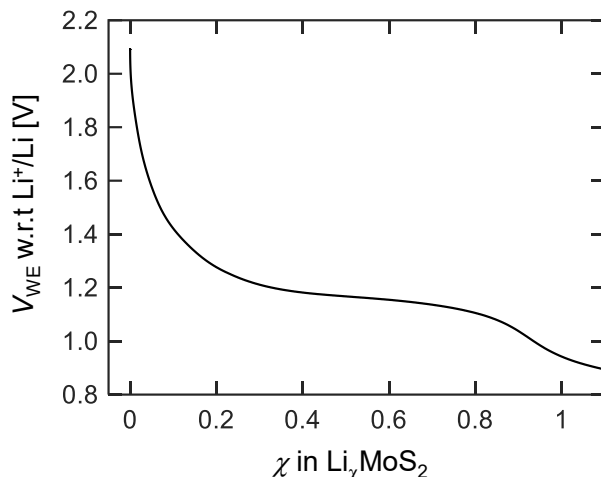
**Supplementary Figure 2 | TDTR measurements of the thermophysical properties of the liquid electrolyte.** **a**, Sample configuration for top-side measurements of the thermal conductivity ( $\kappa_{\text{glass}}$ ) of the transparent fused silica (glass) substrate is: Al/glass. The Al transducer layer is  $\sim 80$  nm thick. We use laser spot sizes ( $1/e^2$  diameters) of  $9.7 \pm 0.2 \mu\text{m}$  and  $6.0 \pm 0.1 \mu\text{m}$  for pump and probe beams, respectively, and a pump modulation frequency of 10 MHz for these measurements; the measured  $\kappa_{\text{glass}} = 1.24 \pm 0.1 \text{ Wm}^{-1}\text{K}^{-1}$ . **b**, Sample configuration for through-substrate measurements is: glass/Al/electrolyte. A few drops of the liquid electrolyte are placed on top of the Al transducer, and encapsulated using a cover slip and epoxy sealant. We make TDTR measurements through the transparent glass (with measured conductivity  $\kappa_{\text{glass}}$ ) and extract the thermal conductivity ( $\kappa_{\text{elec}}$ ), volumetric specific heat ( $C_{\text{elec}}$ ) of the liquid, and thermal boundary conductance at the Al/electrolyte interface ( $G_{\text{Al/elec}}$ ); the measured  $\kappa_{\text{elec}} = 0.25 \pm 0.04 \text{ Wm}^{-1}\text{K}^{-1}$  and  $C_{\text{elec}} = 2.4 \pm 0.1 \text{ Jcm}^{-3}\text{K}^{-1}$ . Error bars are based on uncertainties in  $t_{\text{Al}} (\pm 1 \text{ nm})$ ,  $w_0 (\pm 2 \%)$  and  $\kappa_{\text{glass}} (\pm 0.1 \text{ Wm}^{-1}\text{K}^{-1})$ . As the measurements are not very sensitive to  $G_{\text{Al/elec}}$ , we find that a range of values fit the data reasonably well, between 60 to 100  $\text{MWm}^{-2}\text{K}^{-1}$ . These are within the range of values reported in literature for interfaces between metals and liquids<sup>4</sup>. **c**, TDTR time-decay curves and best fits to the thermal model corresponding to measurements in **a** and **b**.



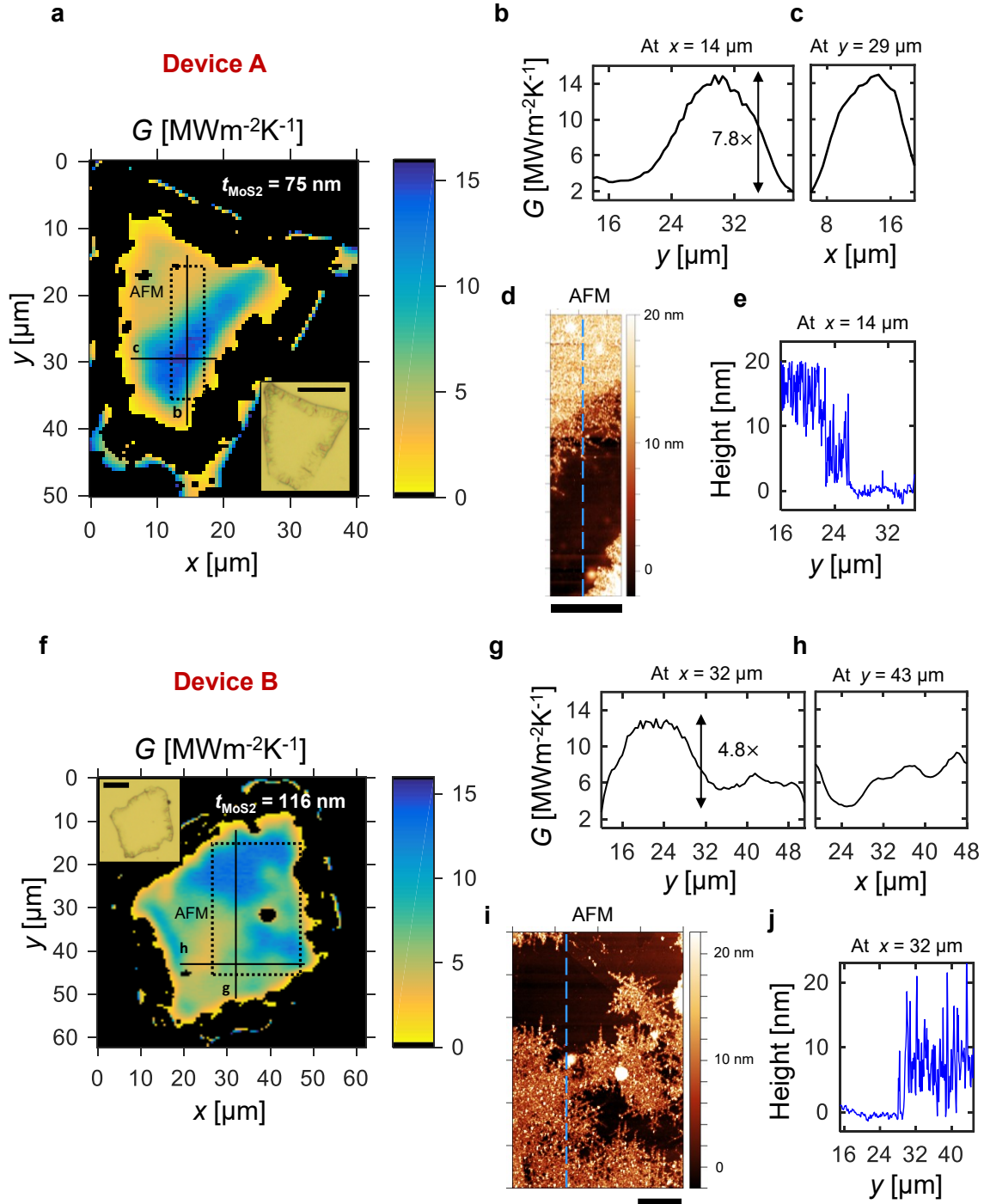
**Supplementary Figure 3 | TDTR sensitivity, signal conversion and error propagation analyses for operando measurements.** **a**, Cross-sectional schematic of the multilayer stack showing the important thermophysical properties of interest. **b**, Plot of TDTR sensitivity coefficients, calculated by dividing the fractional change in the ratio ( $= -V_{in}/V_{out}$ ) signal by the fractional perturbation in the thermophysical parameter. Analyses presented in this figure correspond to operando measurements on a 10 nm thick device. We analyze the sensitivity to four parameters here, namely, MoS<sub>2</sub> thickness, cross-plane thermal conductivity, heat capacity, and in-plane thermal conductivity. The solid and dotted lines correspond to effective cross-plane conductance values of  $G = 2 \text{ MWm}^{-2}\text{K}^{-1}$  and  $16 \text{ MWm}^{-2}\text{K}^{-1}$ , respectively. The arrow indicates the +100 ps time-delay point, where all operando temporal, and both operando and ex situ spatial mapping measurements are taken. **c**, Transfer function relating the TDTR ratio signal at +100 ps to the cross-plane thermal conductance  $G$ . Also shown is a fit to a fourth order polynomial function. The multilayer stack is: electrolyte/Al/MoS<sub>2</sub>/SiO<sub>2</sub>/Si. Assumed thermophysical properties for the various layers in this stack are listed in Supplementary Table 1. **d**, Error propagation analysis for operando TDTR measurements. Plotted are % errors contributed by the various sources of uncertainty. The total error is obtained by adding the individual contributing terms in quadrature (shown as the solid black line). The uncertainties in the individual parameters are:  $w_0$  ( $\pm 2\%$ ),  $\kappa_{elec}$  ( $\pm 0.04 \text{ Wm}^{-1}\text{K}^{-1}$ ),  $C_{elec}$  ( $\pm 0.1 \text{ Jcm}^{-3}\text{K}^{-1}$ ),  $G_{Al/elec}$  ( $\pm 20 \text{ MWm}^{-2}\text{K}^{-1}$ ),  $t_{Al}$  ( $\pm 1 \text{ nm}$ ),  $\kappa_{r,MoS2}$  ( $\pm 20 \text{ Wm}^{-1}\text{K}^{-1}$ ) and  $\kappa_{SiO2}$  ( $\pm 0.1 \text{ Wm}^{-1}\text{K}^{-1}$ ). Also included are uncertainties resulting from  $\delta\Phi = 3 \text{ mrad}$ . At low values of  $G$  when the sample is in the lithiated state, the primary contributors are  $\kappa_{elec}$ ,  $w_0$  and  $\delta\Phi$ . At higher values of  $G$  when the sample is unlithiated, the main contributors are  $w_0$ ,  $\delta\Phi$  and  $\kappa_{SiO2}$ . The total % error is calculated by adding the individual terms in quadrature: it is  $\pm 20\%$  at  $G = 1.6 \text{ MWm}^{-2}\text{K}^{-1}$ , and  $\pm 15\%$  at  $G = 15 \text{ MWm}^{-2}\text{K}^{-1}$ .



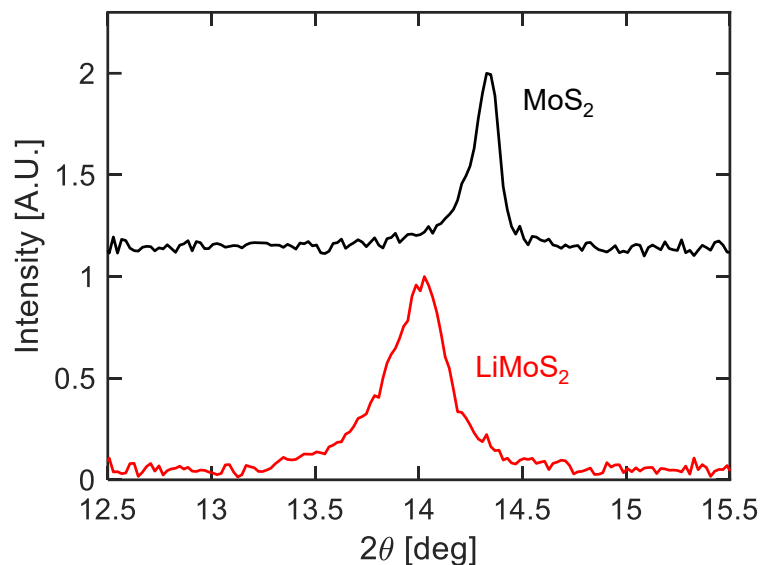
**Supplementary Figure 4 | Perturbative analysis of the operando data shown in Figure 3c. a,** Perturbing the thickness of the MoS<sub>2</sub> film (by  $\pm 15\%$ ) does not change the extracted thermal conductance of the device. The blue curve corresponds to the baseline case, while the red curves correspond to the thickness perturbed by  $\pm 15\%$ ; the curves coincide. The operando measurements are insensitive to possible lithiation-induced variations in the film thickness. **b,** Perturbing the MoS<sub>2</sub> heat capacity by a large amount ( $\pm 50\%$ ) does not significantly change the extracted thermal conductance. We note that the heat capacity could increase upon lithiation, due to the additional modes in the phonon dispersion. However, any impact of these variations on the extracted thermal conductance is very small. The blue curve is the baseline case, while the red curves correspond to MoS<sub>2</sub> heat capacity perturbed by  $\pm 50\%$  relative to the pure MoS<sub>2</sub> value. In the fully lithiated state (lowest  $G$ ), where the heat capacity is expected to change the most, the perturbation in  $G$  is at most  $2.5\%$ .



**Supplementary Figure 5 | Galvanostatic discharge curve for vertically aligned MoS<sub>2</sub> nano-film** (data from Wang et al.<sup>5</sup>, shown here to aid discussion). The plateau at  $V_{\text{WE}} \sim 1.1$  V indicates the 2H to 1T phase transition. At  $V_{\text{WE}} = 1$  V, the sample reaches a lithium composition close to  $\chi = 1$ . This voltage limit is used to estimate the average Li composition  $\chi$  in  $\text{Li}_\chi\text{MoS}_2$  in the galvanostatic experiments shown in the main text (Figure 3), for the 10 nm thick MoS<sub>2</sub> film. In our galvanostatic experiments, we do not use the current-time product to estimate  $\chi$  since it is challenging to accurately determine the mass of an isolated MoS<sub>2</sub> nano-crystal, and because the fabrication process results in multiple crystals being contacted by the Al electrode (i.e. we do not know exactly how much current flows into the flake of interest). To first order, we use  $V_{\text{WE}}$  to estimate  $\chi$ , relying on the fact that in a galvanostatic (i.e. constant current) experiment, the average Li composition increases linearly with time as  $V_{\text{WE}}$  is varied between the limits corresponding to  $\chi = 0$  and  $\chi = 1$  (at  $V_{\text{WE}} = 1$  V). It is important to note that here  $\chi$  is the spatially averaged Li concentration inside the device. As revealed by the thermal conductance imaging experiments shown in Figure 2, the local Li concentration is spatially non-uniform. We also note that in the galvanostatic voltage curves shown in Figure 3b, we do not see a plateau at  $V_{\text{WE}} = 1.1$  V. This is attributed to the dominant capacitive contribution from the metal electrode, and the fast lithiation and delithiation rates (nearly 8.5 C).

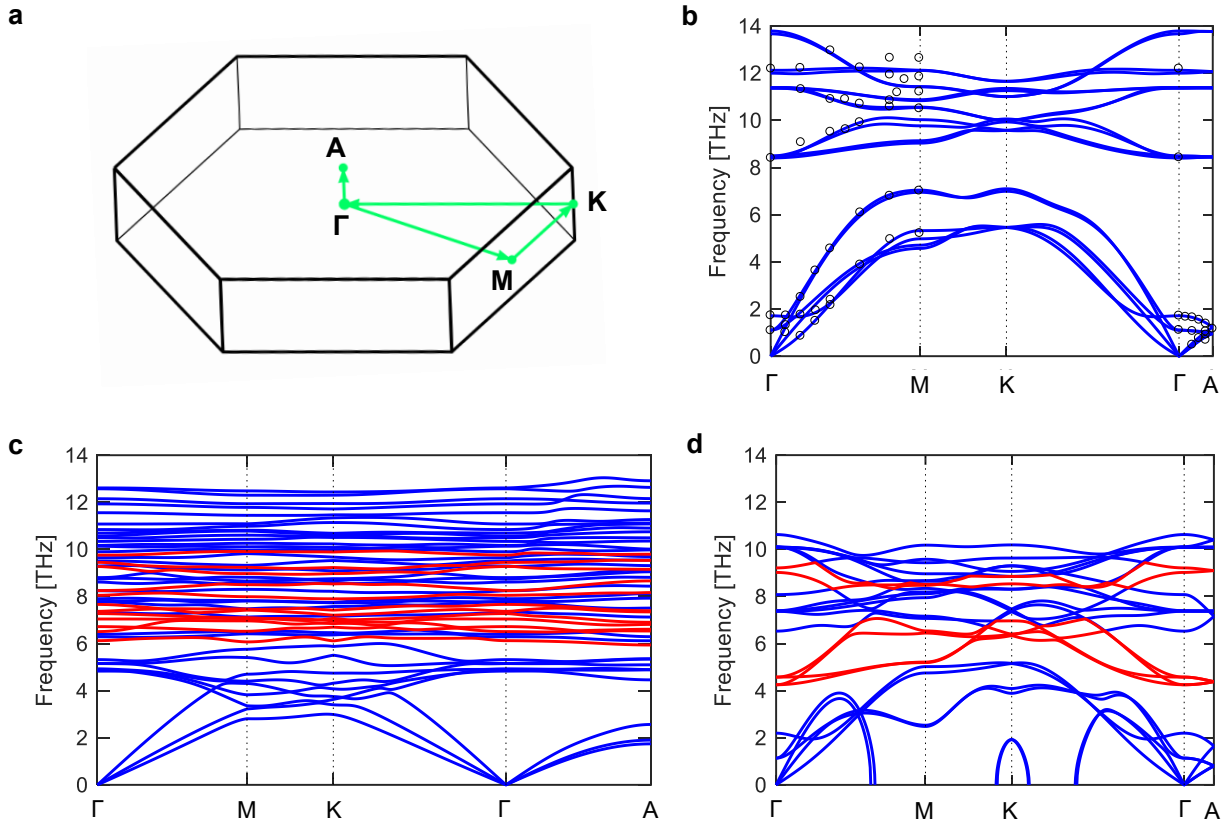


**Supplementary Figure 6 | TDTR and correlative AFM data on two additional ex situ chemically lithiated devices.** a-e, Device A, a 75 nm thick MoS<sub>2</sub> film. f-j, Device B, a 116 nm thick MoS<sub>2</sub> film. Shown in both cases are horizontal (c, h) and vertical (b, g) line scans. The maximum conductance contrast is 7.8× and 4.8× for device A and B, respectively. In both cases, AFM scans shows a clear correlation between topography and thermal conductance (d, i). The smooth unlithiated region has a higher conductance as compared to the rough lithiated region, which is also thicker on average (line scans in e, j). Scale bars in the optical micrographs (a and f) are 20 μm, and in the AFMs (d and i) are 5 μm.

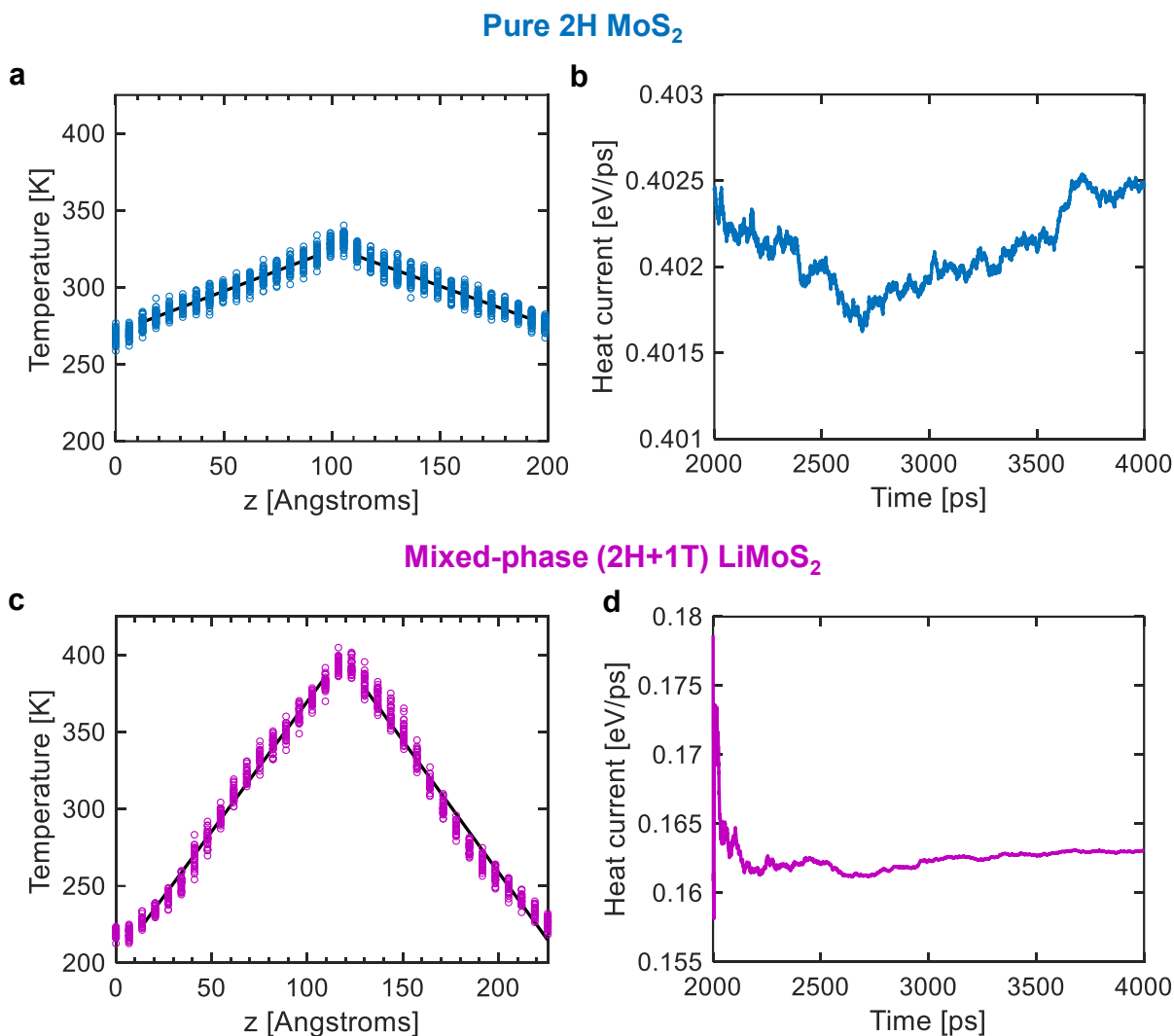


**Supplementary Figure 7 | X-ray diffraction (XRD) measurements of MoS<sub>2</sub> and LiMoS<sub>2</sub> nano-powders.** The (002) peaks corresponding to the out-of-plane lattice constant are located at  $2\theta = 14.34^\circ$  and  $14.02^\circ$ , for the unlithiated and lithiated samples, respectively, corresponding to c-axis lattice constants of 6.17 Å and 6.31 Å. This gives an estimated expansion of approximately 2.3 % along the c-axis due to Li intercalation. These samples were prepared by mixing MoS<sub>2</sub> particles (Sigma-Aldrich) with super P, coating the resulting slurry onto Al foil (cathode), and constructing an electrochemical cell with Li metal (anode), and 1 M LiPF<sub>6</sub> in EC/DEC as the electrolyte. Constant current was used to intercalate Li into MoS<sub>2</sub>, and stopped at a voltage of 0.9 V vs Li<sup>+</sup>/Li. The MoS<sub>2</sub> electrode was taken out from the pouch cell inside the glovebox and sealed by a Kapton tape for XRD measurements; the unlithiated MoS<sub>2</sub> was also covered by Kapton tape for comparison.

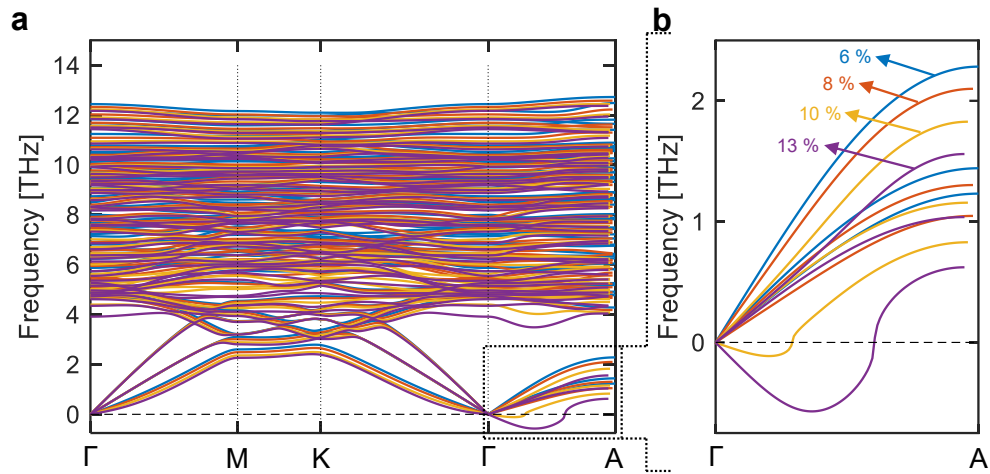




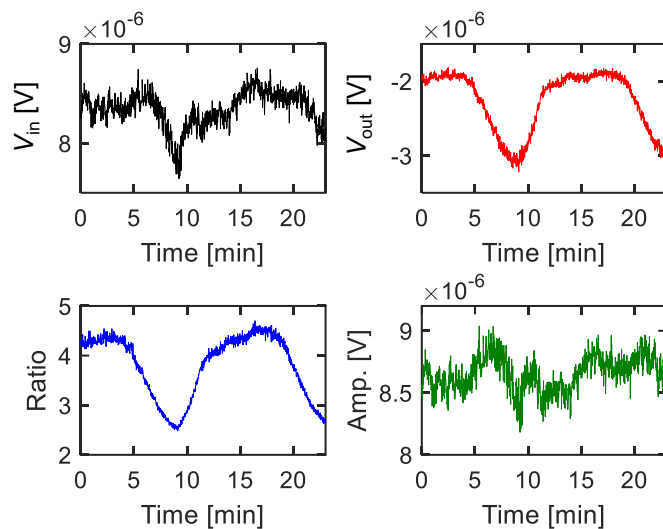
**Supplementary Figure 8 | First principles DFT-LDA (density functional theory-local density approximation) phonon dispersion curves for the full Brillouin zone shown along high symmetry directions  $\Gamma$ -M-K- $\Gamma$ -A. a**, Schematic of Brillouin zone, showing the high-symmetry points along which the phonon dispersion curves have been plotted. **b**, Pure 2H-MoS<sub>2</sub>. Black circles are neutron diffraction data for a bulk MoS<sub>2</sub> crystal from Wakabayashi et al.<sup>6</sup> showing good agreement with the calculations. **c**, 1T-Li<sub>1</sub>MoS<sub>2</sub> and **d**, 2H-Li<sub>1</sub>MoS<sub>2</sub>, where modes are color-coded depending on whether they are MoS<sub>2</sub>-like (blue) or Li-like (red). Soft acoustic in-plane modes occur in the thermodynamically unstable 2H lithiated phase. However, the cross-plane modes, which are most relevant to our thermal transport calculations, exhibit real eigenvalues.



**Supplementary Figure 9 | Molecular Dynamics snapshots.** **a**, Temperature profile and **b**, Stationary heat current for the simulation of a 10 nm thick, pure (unlithiated) 2H-MoS<sub>2</sub> film. **c**, Temperature profile and **d**, Stationary heat current for the simulation of a 10 nm thick mixed-phase system consisting of {4, 3, 4, 2, 4} layers of {2H, 1T, 2H, 1T, 2H}, corresponding to the snapshot shown in Figure 5f.



**Supplementary Figure 10 | Stability of strained 1T-Li<sub>1</sub>MoS<sub>2</sub>.** **a.** Ab initio phonon dispersion calculations of 1T-Li<sub>1</sub>MoS<sub>2</sub> under increasing c-axis tensile strain (6, 8, 10 and 13 %, relative to un lithiated 2H-MoS<sub>2</sub>). **b.** Zoom-in of the acoustic branches along the cross-plane direction ( $\Gamma$ -A). Phonon frequencies become negative for strains > 8 %, indicating structural instability.



**Supplementary Figure 11 | Raw TDTR data corresponding to the galvanostatic thermal conductance modulation experiment shown in Figure 3.** This figure plots  $V_{in}$ ,  $V_{out}$ , ratio ( $= -V_{in}/V_{out}$ ) and amplitude ( $= [V_{in}^2 + V_{out}^2]^{0.5}$ ) data at +100 ps time delay as a function of intercalation time. At this short time delay,  $V_{in}$  is relatively less sensitive to  $G$  as compared to  $V_{out}$ <sup>7</sup>. We see that  $V_{in}$  changes by ~8 %, while  $V_{out}$  changes by ~63 % over one electrochemical cycle.

Parameter	Value	Source
$1/e^2$ spot dia. (pump/probe) [ $w_0$ ]	4.0 $\mu\text{m}$ / 2.7 $\mu\text{m}$	Beam profiler, Knife edge technique <sup>8</sup>
Electrolyte conductivity [ $\kappa_{\text{elec}}$ ]	0.25 $\text{Wm}^{-1}\text{K}^{-1}$	TDTR on: <i>glass/Al/electrolyte</i>
Electrolyte specific heat [ $C_{\text{elec}}$ ]	2.4 $\text{Jcm}^{-3}\text{K}^{-1}$	TDTR on: <i>glass/Al/electrolyte</i>
TBC: Elec / Al [ $G_{\text{Al/elec}}$ ]	60 – 100 $\text{MWm}^{-2}\text{K}^{-1}$	TDTR on: <i>glass/Al/electrolyte</i>
Al thickness [ $t_{\text{Al}}$ ]	79.7 nm	AFM
Al conductivity [ $\kappa_{\text{Al}}$ ]	160 $\text{Wm}^{-1}\text{K}^{-1}$	In-plane electrical + WF law
Al specific heat [ $C_{\text{Al}}$ ]	2.44 $\text{Jcm}^{-3}\text{K}^{-1}$	Literature <sup>9</sup>
TBC: Al / $\text{MoS}_2$	$\infty$	-
$\text{MoS}_2$ thickness [ $t_{\text{MoS}_2}$ ]	9.8 nm	AFM
$\text{MoS}_2$ in-plane conductivity [ $\kappa_{\text{r,MoS}_2}$ ]	45 – 85 $\text{Wm}^{-1}\text{K}^{-1}$	Literature <sup>2,3</sup>
$\text{MoS}_2$ specific heat [ $C_{\text{MoS}_2}$ ]	1.89 $\text{Jcm}^{-3}\text{K}^{-1}$	Literature <sup>10</sup>
TBC: $\text{MoS}_2$ / $\text{SiO}_2$	$\infty$	-
$\text{SiO}_2$ thickness [ $t_{\text{SiO}_2}$ ]	90 nm	Ellipsometry
$\text{SiO}_2$ conductivity [ $\kappa_{\text{SiO}_2}$ ]	1.4 $\text{Wm}^{-1}\text{K}^{-1}$	TDTR on: <i>Al/SiO<sub>2</sub>/Si</i>
$\text{SiO}_2$ specific heat [ $C_{\text{SiO}_2}$ ]	1.62 $\text{Jcm}^{-3}\text{K}^{-1}$	Literature <sup>11</sup>
Si conductivity [ $\kappa_{\text{Si}}$ ]	120 $\text{Wm}^{-1}\text{K}^{-1}$	Literature <sup>12</sup>
TBC: $\text{SiO}_2$ / Si	$\infty$	-
Si specific heat [ $C_{\text{Si}}$ ]	1.66 $\text{Jcm}^{-3}\text{K}^{-1}$	Literature <sup>13</sup>

**Supplementary Table 1 | Thermophysical properties used in the analysis of the operando TDTR data shown in Figure 2 and 3.** The multilayer stack is: electrolyte/Al/ $\text{MoS}_2$ / $\text{SiO}_2$ /Si. TBC - thermal boundary conductance, WF - Wiedemann Franz.

<b>(a) Local density approximation (LDA) unit cell lattice constants</b>				
System	$a$ (Å)	$c$ (Å)	$a$ -axis expansion	$c$ -axis expansion
2H-MoS <sub>2</sub>	3.142	12.053	-	-
2H-Li <sub>1</sub> MoS <sub>2</sub>	3.147	13.706	0.16 %	13.71 %
1T-Li <sub>1</sub> MoS <sub>2</sub>	6.776	6.054	7.83 %	0.46 %

<b>van der Waals density functional (vdW-DF) unit cell lattice constants</b>				
System	$a$ (Å)	$c$ (Å)	$a$ -axis expansion	$c$ -axis expansion
2H-MoS <sub>2</sub>	3.158	12.284	-	-
2H-Li <sub>1</sub> MoS <sub>2</sub>	3.174	13.844	0.50 %	12.70 %
1T-Li <sub>1</sub> MoS <sub>2</sub>	6.789	6.229	7.49 %	1.42 %

<b>(b) Parameters of the MD Lennard Jones potential</b>				
Pure MoS <sub>2</sub>				
		$\epsilon$ (eV)	$\sigma$ (Å)	$Q$
Mo	Mo	1.2680967	2.7498903	0.955290
S	S	0.0052756604	3.5641044	-0.477645
S	Mo	0.42071173	2.3775319	

LiMoS <sub>2</sub>				
		$\epsilon$ (eV)	$\sigma$ (Å)	$Q$
Mo	Mo	1.2680967	2.7498903	0.744962
S	S	0.0052756604	3.5641044	-0.454885
Li	Li	0.0002208294	3.5501168	0.164809
S	Mo	0.42071173	2.3775319	
Li	Mo	0.0009126005	0.63695992	
Li	S	0.0050032260	2.5784385	

**Supplementary Table 2 | Parameters pertaining to theoretical phonon calculations. a,** DFT lattice constants calculated using local density approximation (LDA). Upon lithiation to Li<sub>1</sub>MoS<sub>2</sub>, the 2H and 1T phases show  $c$ -axis lattice expansion of about 13.7 % and 0.5 %, respectively, relative to unliithiated 2H-MoS<sub>2</sub>. Also shown for comparison are results computed using van der Waals density functional (vdW-DF), which are similar to those computed using LDA. **b,** Parameters of the Lennard Jones empirical potential used in molecular dynamics (MD) calculations. Charges ( $Q$ ) are given in fraction of electron charge.

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